

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2440	SERIAL NO. 10/719,640
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary) <div style="position: absolute; top: 50%; left: 50%; transform: translate(-50%, -50%); border: 2px solid black; border-radius: 50%; padding: 10px; text-align: center;">             SEP 27 2004              U.S. PATENT &amp; TRADEMARK OFFICE           </div>				APPLICANT: Terry L. Gilton et al.	
				FILING DATE November 21, 2003	GROUP 2813

  

U.S. PATENT DOCUMENTS							
*Examiner's Initials	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
AA							
AB							
AC							
AD							
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AI							

  

FOREIGN PATENT DOCUMENTS							
Document Number	Date	Country	Class	Subclass	Translation		
					Yes	No	
AJ							
AK							
AL							

  

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)		
TSP	AM	Lee, Hyun-Yong et al., "Lithographic Properties of SiN <sub>x</sub> and Se <sub>75</sub> Ge <sub>25</sub> Thin Films as the Low-Energy Ion-Beam Resist", Proceedings of the 5 <sup>th</sup> International Conference on Properties and Applications of Dielectric Materials, 25-30 May 1997, p.635-638
	AN	
	AO	

  

EXAMINER	DATE CONSIDERED  10/22/04
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.